



IFW

Docket Number: 061063-0316598

PATENT APPLICATION

Client Reference: OSP-18418

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of

JEA GUN PARK, et al.

Group Art Unit: 2812

Application No.: 10/540,992

Examiner: Unassigned

Filed: June 5, 2006

Confirmation No.: 9014

For: CHEMICAL-MECHANICAL-POLISHING SLURRY COMPOSITION, METHOD FOR PLANARIZING SURFACE OF SEMICONDUCTOR DEVICE USING THE SAME, AND METHOD FOR CONTROLLING SELECTION RATIO OF SLURRY COMPOSITION

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR 1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Copies of cited U.S. patents and patent application publications are not included. Copies of foreign patent documents and non-patent literature are included. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom. Applicants respectfully request the Examiner return an initialed copy of the enclosed Form PTO-1449 to Applicants with the next Office communication to indicate that the references has been considered, per MPEP § 609.

This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

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PATENT APPLICATION

The references were cited in a counterpart foreign application. An English language version of the foreign search report is attached for the Examiner's information.

Respectfully Submitted,
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To: Atty. Dkt. No.	M#	Client Ref.
061063	0316598	OSP-18418

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Applicant: Jea Gun PARK et al.

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Examiner: Unassigned Group Art Unit: 2812

U.S. PATENT DOCUMENTS

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
/MA/	AR 2002/0119662 A1	August 29, 2002	KOBAYASHI			
	BR					
	CR					
	DR					
	ER					
	FR					
	GR					
	HR					
	IR					
	JR					
	KR					
	LR					
	MR					
	NR					

FOREIGN PATENT DOCUMENTS

ORIGINAL PATENT DOCUMENT						Abstract		Readily Available	
		Document Number	Date MM/YYYY	Country	Inventor Name				
						Enclosed	No	Enclose	No
	OR								
	PR								
	QR								
	RR								
	SR								
	TR								
	UR								
	VR								
	WR								
	XR								

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

/MA/	YR	J.Y. KIM et al., "Effect of Crystallinity of Ceria Particles on the PETEOS Removal Rate in Chemical Mechanical Polishing for Shallow Trench Isolation", Journal of the Korean Physical Society, vol. 41, No. 4, October 2002, pps. 413-416.				X
	ZR	Supplementary European Search Report				X
	AAR					
	BBR					
	CCR					

Examiner /Maki Angadi/ Date Considered: 04/18/2007

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.